

Notice of References Cited	Application/Control No. 10/581,633		Applicant(s)/Patent Under Reexamination SHIMA ET AL.	
	Examiner ANNA L. VERDERAME		Art Unit 1795	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-2004/0247891	12-2004	Kim et al.	428/426
*	B	US-5,401,609	03-1995	Haratani et al.	430/270.12
	C	US-			
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	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N	JP-09-296266	11-1997	Japan	Shimizu et al.	
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NON-PATENT DOCUMENTS

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	U	Salama. RF Sputtered Aluminum Oxide Films on Silicon. Toronto University Department of Electrical Engineering(1970).
	V	translation JP-09-296266(11/1997)
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.